

Applied Materials Mirra Integra Poly/STI CMP

Serial Number L-402

Currently Configured for 200mm wafer size MFG Date: 1999

EQUIPMENT DETAILS:

• Wafer Size (inches): 8

• Install Type: Through-the-wall

Date of Manufacture: 06/28/99

• Software Version: MB60a1

• CPU Board Type:

Pentium 3 400MHz or

Higher: Yes

• Electrical Requirements: 200/208VAC

• Process Type: Polysilicon

• Mainframe: Mirra

Track o Dry In/Dry

Out

o Signal Lamp Tower

o Integrated SMIF (qty 3 loaders)

o Cassette Tank: Standard

o Robot Type: 112"

o Cleaner Type: Ontrak

o Cleaner Chemicals Used: NH4OH

o E-Chain Lifetime: Since installation

o Cleaning Package: No

o Spray Gun: Single

o In-Situ Removal Rate Monitor: Motor

Torque

o Metrology Option: None

o IPM: No

• Mirra Polish

- Heads o Titan 1 Polish Heads
- o PPS Retaining Rings
- o Standard Wafer Loss Sensor
- Mirra Platens
- o Teflon Coated Platens: No
- o Pad Type: IC 1000
- o Pad Conditioner Head: P4
 - **Intel**
- o Pad Conditioner Disc: EWHA
- o Universal Disk Holder: No
- o Temperature Control : None
- Slurries
- o Slurries/Platen Used: 1
- o Chemicals Used: Oxide Slurry
- o Flow Rate: Standard
- o Dispense Arm: Standard
- o Slurry Flow Monitors: Yes









